

Carrier Loading System - Fast (CLF)

Carrier the Loading System - Fast is used for the automatic loading and unloading of wafer out/in the wafer cartridges. The selected wafer can be taken out of the cartridge via a vacuum grip arm and be put down on a platform.

Here the vacuum arm without rotation proceeds forward/backward, whereby very fast discharge processes can be realized.

The vacuum grip arm is optimized on careful wafer handling - i.e. very small bearing surface.

Each one type of wafer per equipment is applicable - alternatively can be processed 4"/6" or 8".

Optionally the equipment can be equipped with a OCR recognition.



Electrical connection data

Supply voltage	110 – 240 V
Capacity maximally	200 Watt
Frequency	50/60 Hz
Safety class system	I
Connecting cable	US, Euro, UK or Japan
Connection	Cold device plug 3-pin

Vakuum

Vacuum	-65 KPa (-19inchHg)
Vacuum hose connector	ID 6, AD 8

Generally

Width	280 mm
Height	630 mm
Depth	900 mm
Weight	about 45 kg

Order remarks

30189	CLF 4+6"
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